

PATENT

MEC197.001CP1

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Chetan Singh Solanki
Appl. No. : 10/670,754
Filed : September 24, 2003
For : METHOD AND APPARATUS
FOR CONTINUOUS
FORMATION AND LIFT-OFF OF
POROUS SILICON LAYERS
Examiner : Evan T. Pert
Group Art Unit : 2829

CERTIFICATE OF MAILING

I hereby certify that this correspondence and all marked attachments are being deposited with the United States Postal Service as first-class mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on

March 8, 2005
(Date)

John M. Carson, Reg. No. 34,303

AMENDMENT

Mail Stop Amendment

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

In response to the Office Action dated October 20, 2004, Applicant submits the following amendment and remarks for consideration in connection with the above-identified patent application.

Amendments to the Specification begin on page 2 of this paper.

Amendments to the Claims are reflected in the listing of claims which begins on page 5 of this paper.

Amendments to the Drawings begin on page 8 of this paper. A "Replacement Sheet" for each sheet of drawings being amended can be found in the Appendix.

Remarks/Arguments begin on page 9 of this paper.